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APPLICATION NO. FILING DATE		FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.		
10/754,531	01/12/2004	Kazuhito Takanashi	00862.023399	8252		
5514	7590 09/19/2005		EXAMINER			
	ICK CELLA HARPER ELLER PLAZA	AHMED, SHAMIM				
	L, NY 10112		ART UNIT	PAPER NUMBER		
	•		1765			
		DATE MAIL ED: 09/19/2005				

Please find below and/or attached an Office communication concerning this application or proceeding.

· ·		/	Application	No.	Applicant(s)					
Office Action Summary			10/754,531		TAKANASHI ET AL.					
			Examiner		Art Unit					
			Shamim Ahr		1765					
	The MAILING DATE of this communication appears on the cover sheet with the correspondence address Period for Reply									
A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) OR THIRTY (30) DAYS, WHICHEVER IS LONGER, FROM THE MAILING DATE OF THIS COMMUNICATION.  - Extensions of time may be available under the provisions of 37 CFR 1.136(a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication.  - If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication.  - Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133).  Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).										
Status										
1)🛛	Responsive to communication(s) filed on <u>12 January 2004</u> .									
2a)□	This action is <b>FINAL</b> . 2b)⊠ This action is non-final.									
	Since this application is in condition for allowance except for formal matters, prosecution as to the merits is									
,	closed in accordance with the practice under Ex parte Quayle, 1935 C.D. 11, 453 O.G. 213.									
Disposition of Claims										
4)🖂	☑ Claim(s) <u>1-17</u> is/are pending in the application.									
	4a) Of the above claim(s) <u>6-15</u> is/are withdrawn from consideration.									
5)□	5) Claim(s) is/are allowed.									
6)⊠	6)⊠ Claim(s) <u>1-5,16 and 17</u> is/are rejected.									
7)										
8) Claim(s) are subject to restriction and/or election requirement.										
Application Papers										
9) The specification is objected to by the Examiner.										
10)⊠ The drawing(s) filed on <u>12 January 2004</u> is/are: a)⊠ accepted or b)□ objected to by the Examiner.										
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).										
	Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d).									
11)	11) The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.									
Priority ι	under 35 U.S.C. § 119									
<ul> <li>12) Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).</li> <li>a) All b) Some * c) None of:</li> <li>1. Certified copies of the priority documents have been received.</li> <li>2. Certified copies of the priority documents have been received in Application No</li> <li>3. Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).</li> <li>* See the attached detailed Office action for a list of the certified copies not received.</li> </ul>										
2) 🔲 Notic	t(s) e of References Cited (PTO-892) e of Draftsperson's Patent Drawing Review (I mation Disclosure Statement(s) (PTO-1449 o			) ☐ Interview Summary Paper No(s)/Mail Da ) ☐ Notice of Informal P	ate	O-152)				
Paper No(s)/Mail Date  6) Other:										

Application/Control Number: 10/754,531 Page 2

Art Unit: 1765

#### **DETAILED ACTION**

#### Election/Restrictions

- 1. Restriction to one of the following inventions is required under 35 U.S.C. 121:
  - Claims 1-5 and 16-17, drawn to a process, classified in class 216, subclass 58.
  - Claims 6-15, drawn to an apparatus, classified in class 156, subclass 345.37.

The inventions are distinct, each from the other because of the following reasons:

- 2. Inventions I and II are related as process and apparatus for its practice. The inventions are distinct if it can be shown that either: (1) the process as claimed can be practiced by another materially different apparatus or by hand, or (2) the apparatus as claimed can be used to practice another and materially different process. (MPEP § 806.05(e)). In this case the apparatus can be used to practice another and materially different process such as deposition or coating process.
- 3. Because these inventions are distinct for the reasons given above and have acquired a separate status in the art as shown by their different classification, restriction for examination purposes as indicated is proper.
- 4. During a telephone conversation with Jason Okun on 9/13/05 a provisional election was made with traverse to prosecute the invention of Group I, claims 1-5 and 16-17. Affirmation of this election must be made by applicant in replying to this Office

Art Unit: 1765

action. Claims 6-15 are withdrawn from further consideration by the examiner, 37 CFR 1.142(b), as being drawn to a non-elected invention.

5. Applicant is reminded that upon the cancellation of claims to a non-elected invention, the inventorship must be amended in compliance with 37 CFR 1.48(b) if one or more of the currently named inventors is no longer an inventor of at least one claim remaining in the application. Any amendment of inventorship must be accompanied by a request under 37 CFR 1.48(b) and by the fee required under 37 CFR 1.17(i).

## **Specification**

6. The disclosure is objected to because of the following informalities: At page 9, line 26, the use of word "Wh n" is a typographic error.

Appropriate correction is required.

### Claim Rejections - 35 USC § 102

7. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

- (b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.
- 8. Claims 1-2,4-5 are rejected under 35 U.S.C. 102(b) as being anticipated by Tanaka et al (5,174,855).

Tanaka et al teach a process of etching silicon oxide layer considered to be fragile and porous with a vaporized etchant such as hydrogen fluoride solution, wherein the solution is heated using a heater (col.6, lines 57-62).

Application/Control Number: 10/754,531 Page 4

Art Unit: 1765

Tanaka et al also teach that the solution temperature is maintain at 50 degree C (col.12, lines 61-67).

9. Claims 1-2 are rejected under 35 U.S.C. 102(b) as being anticipated by Seefeldt et al (6,118,164).

Seefedt et al teach a process of etching or removing porous silicon oxide layer with vaporous hydrofluoric acid (col.9, lines 39-42).

# Claim Rejections - 35 USC § 103

- 10. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
  - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.
- 11. This application currently names joint inventors. In considering patentability of the claims under 35 U.S.C. 103(a), the examiner presumes that the subject matter of the various claims was commonly owned at the time any inventions covered therein were made absent any evidence to the contrary. Applicant is advised of the obligation under 37 CFR 1.56 to point out the inventor and invention dates of each claim that was not commonly owned at the time a later invention was made in order for the examiner to consider the applicability of 35 U.S.C. 103(c) and potential 35 U.S.C. 102(e), (f) or (g) prior art under 35 U.S.C. 103(a).
- 12. Claims 1-5 and 16-17 are rejected under 35 U.S.C. 103(a) as being unpatentable over Yasukawa (6,232,142) in view of Tanaka (5,174,855).

Art Unit: 1765

Yasukawa teaches a process of forming a semiconductor device including the steps of forming a fragile layer or porous silicon layer (17) on a silicon substrate (16) and forming another substrate (2), which resemble as the claimed transfer layer (col.16, lines 29-31).

Yasukawa also teaches bonding or adhering the silicon substrate including the transfer layer (2) with another substrate (1) to form a bonded stack structure 9col.16, liens 43-50).

Yasukawa further teaches the porous silicon layer is selectively removed by etching using hydrogen fluoride and hydrogen peroxide solution (col.16, lines 55-60).

Yasukawa fail to teach the etching is performed in a vaporized condition.

However, Tanaka et al teaches a surface treatment or etching process of silicon containing layer using hydrogen fluoride solution (see above in the paragraph 8) with the advantage of vaporized etching over liquid etching such as with better and easy control of the etching component (col.4, lines 45-62 and col.5, lines 1-12).

Therefore, it would have been obvious to one of ordinary skilled in the art at the time of claimed invention to modify Yasukawa's process with Tanaka et al's teaching for better and easy process control s taught by Tanaka et al.

#### Conclusion

13. The prior art made of record and not relied upon is considered pertinent to applicant's disclosure. PTO-892 listed related documents that concern with vapor etching silicon substrate.

Art Unit: 1765

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Shamim Ahmed whose telephone number is (571) 272-1457. The examiner can normally be reached on M-Thu (7:00-5:30) Every Friday Off.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Nadine G. Norton can be reached on (571) 272-1465. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Shamim Ahmed Primary Examiner Art Unit 1765

SA September 15, 2005